

Inventor Name Search Result

Your Search was:

Last Name = NAKAMURA

First Name = TOSHITAKA

Application#	Patent#	Status	Date Filed	Title	Inventor Name 10
<u>10477596</u>	Not Issued	019	01/01/0001	METHOD FOR TREATING OSTEOCHONDROSIS AND APPARATUS FOR TREATING OSTEOCHONDROSIS	NAKAMURA ET AL, TOSHITAKA
<u>10224598</u>	Not Issued	020	08/21/2002	STRUCTURE FOR PREVENTING GLASS FROM BREAKING AND PLASMA DISPLAY DEVICE	NAKAMURA, TOSHITAKA
<u>10145119</u>	Not Issued	061	05/15/2002	GLASS CRACK PREVENTION FILM-LIKE LAYER AND PLASMA DISPLAY DEVICE	NAKAMURA, TOSHITAKA
<u>09808104</u>	6548177	150	03/15/2001	TRANSPARENT SHOCK-ABSORBING LAMINATE AND FLAT PANEL DISPLAY USING THE SAME	NAKAMURA, TOSHITAKA
<u>09746228</u>	Not Issued	071	12/26/2000	TRANSPARENT LAMINATE, METHOD FOR PRODUCING THE SAME, AND PLASMA DISPLAY PANEL	NAKAMURA, TOSHITAKA
<u>09729785</u>	6569516	150	12/06/2000	TRANSPARENT LAMINATE AND PLASMA DISPLAY PANEL FILTER UTILIZING SAME	NAKAMURA, TOSHITAKA
<u>09608006</u>	6398900	150	06/30/2000	METHOD OF STICKING TRANSPARENT ELECTROMAGNETIC WAVE SHIELD FILM	NAKAMURA, TOSHITAKA
<u>09458805</u>	6235398	150	12/10/1999	TRANSPARENT LAMINATE AND PLASMA DISPLAY PANEL FILTER UTILIZING SAME	NAKAMURA, TOSHITAKA
<u>09455904</u>	6252703	150	12/07/1999	TRANSPARENT LAMINATE AND FILTER FOR USE FOR PLASMA DISPLAY PANEL USING THE TRANSPARENT LAMINATE	NAKAMURA, TOSHITAKA
<u>09404709</u>	6333592	150	09/24/1999	FILTER FOR PLASMA DISPLAY PANEL	NAKAMURA, TOSHITAKA

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Inventor Name Search Result

Your Search was:

Last Name = MIYAUCHI

First Name = KAZUHIKO

Application#	Patent#	Status	Date Filed	Title	Inventor Name 10
<u>10288441</u>	Not Issued	030	11/06/2002	GLASS-BREAK PREVENTING FILM LIKE FILTER AND PLASMA DISPLAY APPARATUS	MIYAUCHI, KAZUHIKO
<u>10274986</u>	Not Issued	030	10/22/2002	TRANSPARENT PRESSURE-SENSITIVE ADHESIVE COMPOSITION AND PRESSURE-SENSITIVE ADHESIVE SHEET THEREOF	MIYAUCHI, KAZUHIKO
<u>10224598</u>	Not Issued	020	08/21/2002	STRUCTURE FOR PREVENTING GLASS FROM BREAKING AND PLASMA DISPLAY DEVICE	MIYAUCHI, KAZUHIKO
<u>10145119</u>	Not Issued	061	05/15/2002	GLASS CRACK PREVENTION FILM-LIKE LAYER AND PLASMA DISPLAY DEVICE	MIYAUCHI, KAZUHIKO
<u>09808104</u>	6548177	150	03/15/2001	TRANSPARENT SHOCK-ABSORBING LAMINATE AND FLAT PANEL DISPLAY USING THE SAME	MIYAUCHI, KAZUHIKO
<u>09746228</u>	Not Issued	071	12/26/2000	TRANSPARENT LAMINATE, METHOD FOR PRODUCING THE SAME, AND PLASMA DISPLAY PANEL	MIYAUCHI, KAZUHIKO
<u>09729785</u>	6569516	150	12/06/2000	TRANSPARENT LAMINATE AND PLASMA DISPLAY PANEL FILTER UTILIZING SAME	MIYAUCHI, KAZUHIKO
<u>09608006</u>	6398900	150	06/30/2000	METHOD OF STICKING TRANSPARENT ELECTROMAGNETIC WAVE SHIELD FILM	MIYAUCHI, KAZUHIKO
<u>09458805</u>	6235398	150	12/10/1999	TRANSPARENT LAMINATE AND PLASMA DISPLAY PANEL FILTER UTILIZING SAME	MIYAUCHI, KAZUHIKO
<u>09455904</u>	6252703	150	12/07/1999	TRANSPARENT LAMINATE AND FILTER FOR USE FOR PLASMA DISPLAY PANEL USING THE TRANSPARENT LAMINATE	MIYAUCHI, KAZUHIKO

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Inventor Name Search Result

Your Search was:

Last Name = HIEDA

First Name = YOSHIHIRO

Application#	Patent#	Status	Date Filed	Title	Inventor Name 15
<u>10288441</u>	Not Issued	030	11/06/2002	GLASS-BREAK PREVENTING FILM LIKE FILTER AND PLASMA DISPLAY APPARATUS	HIEDA, YOSHIHIRO
<u>10274986</u>	Not Issued	030	10/22/2002	TRANSPARENT PRESSURE-SENSITIVE ADHESIVE COMPOSITION AND PRESSURE-SENSITIVE ADHESIVE SHEET THEREOF	HIEDA, YOSHIHIRO
<u>10224598</u>	Not Issued	020	08/21/2002	STRUCTURE FOR PREVENTING GLASS FROM BREAKING AND PLASMA DISPLAY DEVICE	HIEDA, YOSHIHIRO
<u>10145119</u>	Not Issued	061	05/15/2002	GLASS CRACK PREVENTION FILM-LIKE LAYER AND PLASMA DISPLAY DEVICE	HIEDA, YOSHIHIRO
<u>09808104</u>	6548177	150	03/15/2001	TRANSPARENT SHOCK-ABSORBING LAMINATE AND FLAT PANEL DISPLAY USING THE SAME	HIEDA, YOSHIHIRO
<u>09746228</u>	Not Issued	071	12/26/2000	TRANSPARENT LAMINATE, METHOD FOR PRODUCING THE SAME, AND PLASMA DISPLAY PANEL	HIEDA, YOSHIHIRO
<u>09729785</u>	6569516	150	12/06/2000	TRANSPARENT LAMINATE AND PLASMA DISPLAY PANEL FILTER UTILIZING SAME	HIEDA, YOSHIHIRO
<u>09608006</u>	6398900	150	06/30/2000	METHOD OF STICKING TRANSPARENT ELECTROMAGNETIC WAVE SHIELD FILM	HIEDA, YOSHIHIRO
<u>09458805</u>	6235398	150	12/10/1999	TRANSPARENT LAMINATE AND PLASMA DISPLAY PANEL FILTER UTILIZING SAME	HIEDA, YOSHIHIRO
<u>09455904</u>	6252703	150	12/07/1999	TRANSPARENT LAMINATE AND FILTER FOR USE FOR PLASMA DISPLAY PANEL USING THE TRANSPARENT LAMINATE	HIEDA, YOSHIHIRO
<u>08530249</u>	5902768	250	09/28/1997	REVERSIBLE HEAT-SENSITIVE RECORDING MATERIAL	HIEDA, YOSHIHIRO
<u>08281687</u>	5472929	150	07/28/1994	REVERSIBLE HEAT-SENSITIVE RECORDING MEDIUM AND	HIEDA, YOSHIHIRO

				MAGNETIC CARD USING THE SAME	
<u>08240528</u>	<u>5604175</u>	150	05/10/1994	REVERSIBLE HEAT-SENSITIVE RECORDING MEDIUM	HIEDA , YOSHIHIRO
<u>07925257</u>	<u>5258350</u>	150	08/06/1992	REVERSIBLE HEAT-SENSITIVE RECORDING MATERIAL AND MAGNETIC CARD USING THE SAME	HIEDA , YOSHIHIRO
<u>07732003</u>	<u>5229350</u>	150	07/18/1991	REVERSIBLE HEAT-SENSITIVE RECORDING MATERIAL AND MAGNETIC CARD USING THE RECORDING MATERIAL	HIEDA , YOSHIHIRO

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Inventor Name Search Result

Your Search was:

Last Name = SASA

First Name = KAZUAKI

Application#	Patent#	Status	Date Filed	Title	Inventor Name 51
10471103	Not Issued	020	09/08/2003	COMPLEX CATALYST, PROCESS FOR PRODUCING THE COMPLEX CATALYST, AND PROCESS FOR PRODUCING ALCHOHOL DERIVATIVE WITH THE COMPLEX CATALYST	SASAKI, KAZUAKI
10407421	Not Issued	030	04/07/2003	TRANSPARENT CONDUCTIVE LAMINATE AND PROCESS OF PRODUCING THE SAME	SASA, KAZUAKI
10304710	Not Issued	030	11/27/2002	SEMICONDUCTOR LIGHT-EMITTING DEVICE	SASAKI, KAZUAKI
10253609	Not Issued	041	09/25/2002	SEMICONDUCTOR LIGHT-EMITTING DEVICE AND METHOD FOR MANUFACTURING THEREOF	SASAKI, KAZUAKI
10198178	Not Issued	030	07/19/2002	MEDICINE, CARRIER FOR MEDICINE, METHOD OF PRODUCING MEDICINE, AND METHOD OF TUMOR TREATMENT	SASAKI, KAZUAKI
10189627	Not Issued	061	07/08/2002	FABRICATION METHOD OF SEMICONDUCTOR LIGHT-EMITTING DEVICE	SASAKI, KAZUAKI
10083575	Not Issued	041	02/27/2002	METHOD FOR PRODUCING OPTICALLY ACTIVE CHRYSANTHEMIC ACID	SASAKI, KAZUAKI
10075284	Not Issued	041	02/15/2002	THERAPEUTIC ULTRASOUND SYSTEM	SASAKI, KAZUAKI
09839114	6399409	150	04/23/2001	METHOD FOR FABRICATING SEMICONDUCTOR LIGHT EMITTING ELEMENT	SASAKI, KAZUAKI
09838592	6476421	150	04/20/2001	SEMICONDUCTOR LIGHT-EMITTING DEVICE AND METHOD FOR MANUFACTURING THEREOF	SASAKI, KAZUAKI
09830423	6511428	150	04/26/2001	ULTRASONIC MEDICAL TREATING DEVICE	SASAKI, KAZUAKI
09801844	6572839	150	03/09/2001	SENSITIZER FOR TUMOR TREATMENT	SASAKI, KAZUAKI
09757689	6399965	150	01/11/2001	SEMICONDUCTOR LIGHT EMITTING DEVICE WITH HIGH YIELD AND LOW POWER CONSUMPTION	SASAKI, KAZUAKI

09746228	Not Issued	071	12/26/2000	TRANSPARENT LAMINATE, METHOD FOR PRODUCING THE SAME, AND PLASMA DISPLAY PANEL	SASA, KAZUAKI
09729785	6569516	150	12/06/2000	TRANSPARENT LAMINATE AND PLASMA DISPLAY PANEL FILTER UTILIZING SAME	SASA, KAZUAKI
09671777	6465812	150	09/27/2000	SEMICONDUCTOR LIGHT EMITTING DEVICE	SASAKI, KAZUAKI
09608006	6398900	150	06/30/2000	METHOD OF STICKING TRANSPARENT ELECTROMAGNETIC WAVE SHIELD FILM	SASA, KAZUAKI
09490534	6468818	150	01/25/2000	METHOD FOR PRODUCING A HIGH-LUMINANCE SEMICONDUCTOR LIGHT- EMITTING DEVICE CAPABLE OF OPERATING AT A LOW VOLTAGE	SASAKI, KAZUAKI
09458805	6235398	150	12/10/1999	TRANSPARENT LAMINATE AND PLASMA DISPLAY PANEL FILTER UTILIZING SAME	SASA, KAZUAKI
09455904	6252703	150	12/07/1999	TRANSPARENT LAMINATE AND FILTER FOR USE FOR PLASMA DISPLAY PANEL USING THE TRANSPARENT LAMINATE	SASA, KAZUAKI
09404709	6333592	150	09/24/1999	FILTER FOR PLASMA DISPLAY PANEL	SASA, KAZUAKI
09238503	6268525	150	01/27/1999	PROCESS FOR PRODUCING OPTICALLY ACTIVE CHRYSANTHEMIC ACID	SASAKI, KAZUAKI
09205184	6074889	150	12/04/1998	METHOD FOR PRODUCING SEMICONDUCTOR LIGHT- EMITTING DEVICE WITH UNDOPED SPACER LAYER	SASAKI, KAZUAKI
09015052	6246078	150	01/28/1998	SEMICONDUCTOR LIGHT EMITTING ELEMENT	SASAKI, KAZUAKI
08742695	6216538	150	11/04/1996	PARTICLE HANDLING APPARATUS FOR HANDLING PARTICLES IN FLUID BY ACOUSTIC RADIATION PRESSURE	SASAKI, KAZUAKI
08668086	5717709	150	06/19/1996	SEMICONDUCTOR LIGHT- EMITTING DEVICE CAPABLE OF HAVING GOOD STABILITY IN FUNDAMENTAL MODE OF OSCILLATION, DECREASING CURRENT LEAKAGE, AND LOWERING OSCILLATION THRESHOLD LIMIT, AND METHOD OF MAKING THE SAME	SASAKI, KAZUAKI
08652357	5856682	150	05/23/1996	SEMICONDUCTOR LIGHT- EMITTING DEVICE AND METHOD FOR PRODUCING THE SAME	SASAKI, KAZUAKI

<u>08435391</u>	<u>5516723</u>	150	05/05/1995	SEMICONDUCTOR LIGHT-EMITTING DEVICE CAPABLE OF HAVING GOOD STABILITY IN FUNDAMENTAL MODE OF OSCILLATION, DECREASING CURRENT LEAKAGE, AND LOWERING OSCILLATION THRESHOLD LIMIT, AND METHOD OF MAKING THE SAME	SASAKI, KAZUAKI
<u>08409067</u>	Not Issued	161	03/23/1995	ALDOL CONDENSATION DEHYDRATION AND CATALYST THEREFOR	SASAKI, KAZUAKI
<u>08314585</u>	<u>5571750</u>	150	09/28/1994	METHOD FOR PRODUCING A SEMICONDUCTOR LASER DEVICE	SASAKI, KAZUAKI
<u>08270115</u>	<u>5404031</u>	150	07/01/1994	SEMICONDUCTOR LIGHT EMITTING DEVICE WITH CURRENT CONFINING LAYER	SASAKI, KAZUAKI
<u>08253363</u>	Not Issued	166	06/03/1994	SEMICONDUCTOR LIGHT-EMITTING DEVICE CAPABLE OF HAVING GOOD STABILITY IN FUNDAMENTAL MODE OF OSCILLATION, DECREASING CURRENT LEAKAGE, AND LOWERING OSCILLATION THRESHOLD LIMIT, AND METHOD OF MAKING THE SAME	SASAKI, KAZUAKI
<u>08163290</u>	Not Issued	166	12/02/1993	PARTICLE HANDLING APPARATUS FOR HANDLING PARTICLES IN FLUID BY ACOUSTIC RADIATION PRESSURE	SASAKI, KAZUAKI
<u>08148329</u>	Not Issued	161	11/08/1993	ALDOL CONDENSATION DEHYDRATION AND CATALYST THEREFOR	SASAKI, KAZUAKI
<u>08056906</u>	Not Issued	161	05/05/1993	MAGNESIUM ALUMINIUM COMPLEX COMPOUNDS, PROCESS FOR PREPARING THE SAME AND PROCESS OF ALDOL CONDENSATION DEHYDRATION PRODUCTS USING THE SAME	SASAKI, KAZUAKI
<u>08025434</u>	Not Issued	166	03/03/1993	SEMICONDUCTOR LIGHT EMITTING DEVICE	SASAKI, KAZUAKI
<u>07998436</u>	<u>5260231</u>	150	12/30/1992	METHOD FOR THE PRODUCTION OF A SEMICONDUCTOR LASER	SASAKI, KAZUAKI
<u>07995064</u>	<u>5413956</u>	150	12/22/1992	METHOD FOR PRODUCING A SEMICONDUCTOR LASER DEVICE	SASAKI, KAZUAKI
<u>07980666</u>	<u>5309001</u>	150	11/24/1992	LIGHT-EMITTING DIODE HAVING A SURFACE ELECTRODE OF A TREE-LIKE FORM	SASAKI, KAZUAKI
<u>07883397</u>	<u>5243081</u>	150	05/15/1992	ALDOL CONDENSATION DEHYDRATION CATALYST, A PROCESS FOR PREPARING THE SAME AND A PROCESS FOR	SASAKI, KAZUAKI

				PREPARING AN ALDOL CONDENSATION DEHYDRATE USING THE PROCESS	
<u>07879583</u>	<u>5237107</u>	150	05/07/1992	MAGNESIUM. ALUMINIUM COMPLEX COMPOUNDS, PROCESS FOR PREPARING THE SAME AND PROCESS OF ALDOL CONDENSATION DEHYDRATION PRODUCTS USING THE SAME	SASAKI , KAZUAKI
<u>07762769</u>	<u>5228047</u>	150	09/20/1991	SEMICONDUCTOR LASER DEVICE AND A METHOD FOR PRODUCING THE SAME	SASAKI , KAZUAKI
<u>07739767</u>	<u>5171706</u>	150	08/01/1991	METHOD FOR THE PRODUCTION OF A SEMICONDUCTOR LASER DEVICE	SASAKI , KAZUAKI
<u>07727375</u>	<u>5208468</u>	150	07/05/1991	SEMICONDUCTOR LASER DEVICE WITH A SULFUR-CONTAINING FILM PROVIDED BETWEEN THE FACET AND THE PROTECTIVE FILM	SASAKI , KAZUAKI
<u>07513508</u>	<u>5042044</u>	150	04/27/1990	SEMICONDUCTOR LASER DEVICE, A SEMICONDUCTOR WAFER	SASAKI , KAZUAKI
<u>07474272</u>	Not Issued	166	02/02/1990	SEMICONDUCTOR LASER DEVICE AND A METHOD FOR THE PRODUCTION OF THE SAME	SASAKI , KAZUAKI
<u>07456673</u>	<u>5022036</u>	150	12/27/1989	SEMICONDUCTOR LASER DEVICE	SASAKI , KAZUAKI
<u>07406903</u>	<u>4984244</u>	250	09/13/1989	SEMICONDUCTOR LASER DEVICE	SASAKI , KAZUAKI
<u>07347099</u>	Not Issued	166	05/03/1989	METHOD FOR THE PRODUCTION OF SEMICONDUCTOR DEVICES	SASAKI , KAZUAKI
<u>07286682</u>	<u>4977568</u>	150	12/19/1988	SEMICONDUCTOR LASER DEVICE	SASAKI , KAZUAKI
<u>06534868</u>	<u>4592623</u>	150	09/22/1983	POLARIZING PLATE	SASA , KAZUAKI

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L Number	Hits	Search Text	DB	Time stamp
1	1	6548177.pn.	USPAT; US-PGPUB	2004/01/12 09:09
2	57	((Nakamura.in. or Sasa.in. or Hieda.in. or Miyauchi.in. or (Nitto adj Denko).as.) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag or (transparent near2 conduct\$3)) with (temperature)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 09:16
3	11	((Nakamura.in. or Sasa.in. or Hieda.in. or Miyauchi.in. or (Nitto adj Denko).as.) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag or (transparent near2 conduct\$3)) with (rate near2 (deposit\$3)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 09:17
4	82	((Nakamura.in. or Sasa.in. or Hieda.in. or Miyauchi.in. or (Nitto adj Denko).as.) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index))))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 09:49
5	52	((Nakamura.in. or Sasa.in. or Hieda.in. or Miyauchi.in. or (Nitto adj Denko).as.) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index))))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 09:21
6	14	((Nakamura.in. or Sasa.in. or Hieda.in. or Miyauchi.in. or (Nitto adj Denko).as.) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and (PDP or (plasma adj display)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 09:19
7	42	((Nakamura.in. or Sasa.in. or Hieda.in. or Miyauchi.in. or (Nitto adj Denko).as.) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) not (((Nakamura.in. or Sasa.in. or Hieda.in. or Miyauchi.in. or (Nitto adj Denko).as.) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and (PDP or (plasma adj display)))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 09:22
8	726	(427/108,109).CCLS.	USPAT; US-PGPUB	2004/01/12 09:22
9	1505	(427/124,125).CCLS.	USPAT; US-PGPUB	2004/01/12 09:22
10	1956	(427/163.1,164,165,166).CCLS.	USPAT; US-PGPUB	2004/01/12 09:23
11	2418	(427/250,255.32,255.7).CCLS.	USPAT; US-PGPUB	2004/01/12 09:23
12	2325	(427/404,419.1,419.2,419.3).CCLS.	USPAT; US-PGPUB	2004/01/12 09:23
13	686	(204/192.1,192.14).CCLS.	USPAT; US-PGPUB	2004/01/12 09:23
14	1991	(204/192.15,192.26,192.28).CCLS.	USPAT; US-PGPUB	2004/01/12 09:24

15	1103	(313/112,489).CCLS.	USPAT; US-PGPUB	2004/01/12 09:24
16	2352	(359/359,360,580,586,588,885,888).CCLS.	USPAT; US-PGPUB	2004/01/12 09:24
17	12990	((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.) ((204/192.15,192.26,192.28).CCLS.) and ((313/112,489).CCLS.) or ((359/359,360,580,586,588,885,888).CCLS.)) ((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.)) and ((sputter\$3 or (vacuum adj dry)) with (Ag or silver) with (temperature)) ((sputter\$3 or (vacuum adj dry)) with (Ag or silver) with (temperature)) (((sputter\$3 or (vacuum adj dry)) with (Ag or silver) with (temperature))) not (((427/108,109).CCLS.) (427/124,125).CCLS.) (427/163.1,164,165,166).CCLS.) (427/250,255.32,255.7).CCLS.) (427/404,419.1,419.2,419.3).CCLS.) (204/192.1,192.14).CCLS.) (204/192.15,192.26,192.28).CCLS.) (313/112,489).CCLS.) (359/359,360,580,586,588,885,888).CCLS.)) and ((sputter\$3 or (vacuum adj dry)) with (Ag or silver) with (temperature))) ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and ((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) (359/359,360,580,586,588,885,888).CCLS.))	USPAT; US-PGPUB USPAT; US-PGPUB USPAT; US-PGPUB	2004/01/12 09:25
18	38	((313/112,489).CCLS.) and ((359/359,360,580,586,588,885,888).CCLS.))	USPAT; US-PGPUB	2004/01/12 09:27
19	20	((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.)) and ((sputter\$3 or (vacuum adj dry)) with (Ag or silver) with (temperature)) ((sputter\$3 or (vacuum adj dry)) with (Ag or silver) with (temperature)) (((sputter\$3 or (vacuum adj dry)) with (Ag or silver) with (temperature))) not (((427/108,109).CCLS.) (427/124,125).CCLS.) (427/163.1,164,165,166).CCLS.) (427/250,255.32,255.7).CCLS.) (427/404,419.1,419.2,419.3).CCLS.) (204/192.1,192.14).CCLS.) (204/192.15,192.26,192.28).CCLS.) (313/112,489).CCLS.) (359/359,360,580,586,588,885,888).CCLS.)) and ((sputter\$3 or (vacuum adj dry)) with (Ag or silver) with (temperature))) ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and ((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) (359/359,360,580,586,588,885,888).CCLS.))	USPAT; US-PGPUB USPAT; US-PGPUB	2004/01/12 09:33
20	168	((sputter\$3 or (vacuum adj dry)) with (Ag or silver) with (temperature))	USPAT; US-PGPUB	2004/01/12 09:33
21	148	((sputter\$3 or (vacuum adj dry)) with (Ag or silver) with (temperature)) not (((427/108,109).CCLS.) (427/124,125).CCLS.) (427/163.1,164,165,166).CCLS.) (427/250,255.32,255.7).CCLS.) (427/404,419.1,419.2,419.3).CCLS.) (204/192.1,192.14).CCLS.) (204/192.15,192.26,192.28).CCLS.) (313/112,489).CCLS.) (359/359,360,580,586,588,885,888).CCLS.)) and ((sputter\$3 or (vacuum adj dry)) with (Ag or silver) with (temperature))) ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and ((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) (359/359,360,580,586,588,885,888).CCLS.))	USPAT; US-PGPUB USPAT; US-PGPUB	2004/01/12 09:33
22	253	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and ((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) (359/359,360,580,586,588,885,888).CCLS.))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 10:02

23	248	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and ((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))) not ((Nakamura.in. or Sasa.in. or Hieda.in. or Miyauchi.in. or (Nitto adj Denko).as.) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index))))))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 09:50
24	30	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and ((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))) not ((Nakamura.in. or Sasa.in. or Hieda.in. or Miyauchi.in. or (Nitto adj Denko).as.) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index))))))	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 09:51
25	102	4mcc4d830mr(papemat\$3jodi\$3ayam adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and ((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))) and ((sputter\$3 or deposit\$3) with temperature)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 09:58

26	154	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and ((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))) and ((sputter\$3 or deposit\$3 or coat\$3) with temperature)	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 09:59
27	135	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and ((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))) and ((sputter\$3 or deposit\$3 or coat\$3) with temperature)) not (((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and ((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))) not ((Nakamura.in. or Sasa.in. or Hieda.in. or Miyauchi.in. or (Nitto adj Denko).as.) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and ((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))) and ((sputter\$3 or deposit\$3 or coat\$3) with temperature)) and (sputter\$3 with	USPAT; US-PGPUB; EPO; JPO; DERWENT; IBM_TDB	2004/01/12 09:58
28	47	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) and ((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))) and ((sputter\$3 or deposit\$3 or coat\$3) with temperature)) and (sputter\$3 with	USPAT; US-PGPUB	2004/01/12 09:59

29	186	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) same (repeat\$3 or multilayer or (multi adj layer) or (multiple adj layer) or (PDP) or (plasma adj display) or filter or stack))	USPAT; US-PGPUB	2004/01/12 10:10
30	27	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) same (repeat\$3 or multilayer or (multi adj layer) or (multiple adj layer) or (PDP) or (plasma adj display) or filter or stack)) and ((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))	USPAT; US-PGPUB	2004/01/12 10:06
31	14	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) same (repeat\$3 or multilayer or (multi adj layer) or (multiple adj layer) or (PDP) or (plasma adj display) or filter or stack)) and ((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature)	USPAT; US-PGPUB	2004/01/12 10:19
32	1844	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))))	USPAT; US-PGPUB	2004/01/12 10:14
33	134	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index))))) and ((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature)	USPAT; US-PGPUB	2004/01/12 10:10
34	120	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index))))) and ((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature)) not (((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) same (repeat\$3 or multilayer or (multi adj layer) or (multiple adj layer) or (PDP) or (plasma adj display) or filter or stack)) and ((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature))	USPAT; US-PGPUB	2004/01/12 10:10

35	386	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3 or PVD) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3 or PVD) with ((high near2 (refract\$3 near2 index)))))	USPAT; US-PGPUB	2004/01/12 10:14
36	114	((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3 or PVD) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3 or PVD) with ((high near2 (refract\$3 near2 index))))) and ((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.))	USPAT; US-PGPUB	2004/01/12 10:15

37	103	<p>(((((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3 or PVD) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3 or PVD) with ((high near2 (refract\$3 near2 index)))))) and ((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.)))</p> <p>not ((((((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))))) and ((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature))) not (((((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) same (repeat\$3 or multilayer or (multi adj layer) or (multiple adj layer) or (PDP) or (plasma adj display) or filter or stack))) and ((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature))) or (((((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) same (repeat\$3 or multilayer or (multi adj layer) or (multiple adj layer) or (PDP) or (plasma adj display) or filter or stack))) and ((427/108,109).CCLS.) ((427/124,125).CCLS.) ((427/163.1,164,165,166).CCLS.) ((427/250,255.32,255.7).CCLS.) ((427/404,419.1,419.2,419.3).CCLS.) ((204/192.1,192.14).CCLS.) ((204/192.15,192.26,192.28).CCLS.) ((313/112,489).CCLS.) ((359/359,360,580,586,588,885,888).CCLS.)))</p> <p>or ((((((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) same (repeat\$3 or multilayer or (multi adj layer) or (multiple adj layer) or (PDP) or (plasma adj display) or filter or stack))) and ((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature))) not (((((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) same (repeat\$3 or multilayer or (multi adj layer) or (multiple adj layer) or (PDP) or (plasma adj display) or filter or stack))) and ((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature)))</p>	USPAT; US-PGPUB	2004/01/12 10:15
38	33	<p>(((((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3 or PVD) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3 or PVD) with ((high near2 (refract\$3 near2 index)))))) and ((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature)))</p>	USPAT; US-PGPUB	2004/01/12 10:21

39	30	(((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3 or PVD) with (silver or Ag)) and ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3 or PVD) with ((high near2 (refract\$3 near2 index)))) and ((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature)) not (((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (silver or Ag)) same ((coat\$3 or deposit\$3 or (vacuum adj dry) or sputter\$3) with (ITO or (indium near2 tin near2 oxide) or (high near2 (refract\$3 near2 index)))) same (repeat\$3 or multilayer or (multi adj layer) or (multiple adj layer) or (PDP) or (plasma adj display) or filter or stack))) and ((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature))	USPAT; US-PGPUB	2004/01/12 10:19
40	291	((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature) and (Ag or silver)	EPO; JPO; DERWENT; IBM_TDB	2004/01/12 10:25
41	92	((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature) with (Ag or silver)	EPO; JPO; DERWENT; IBM_TDB	2004/01/12 10:21
42	22	((sputter\$3 or (vacuum adj (dry or deposit\$3)) or PVD) with temperature) and (Ag or silver)) and (multilayer or (multi adj layer) or stack or filter or PDP or (plasma adj display))	EPO; JPO; DERWENT; IBM_TDB	2004/01/12 10:26